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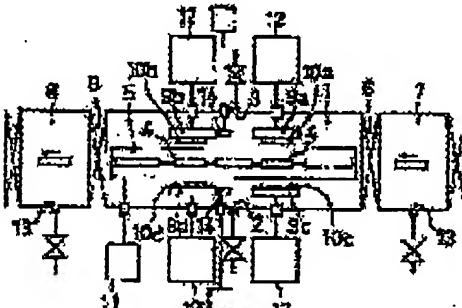
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(54) ELECTRODE FILM FORMING DEVICE FOR CRYSTAL OSCILLATOR

(57) Abstract:

PURPOSE: To obtain the device by which electrodes of two layers or over are formed at once to both sides of a crystal substrate by providing a sputter cathode having a material for plural crystal oscillator use electrode films to both sides of a moving path of the substrate respectively.



films are formed at once to both sides of the crystal substrate.

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